

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: S. KADLEC, et al.  
Serial No: 10/798,331  
Filed: March 12, 2004  
Title: METHOD FOR MANUFACTURING SPUTTER-COATED  
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING  
CHAMBER WITH SUCH SOURCE  
Group: 1795  
Examiner: Michael A. Band  
Conf. No.: 6134

**AMENDMENT UNDER 37 CFR 1.312**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 29, 2010

Sir:

The following amendments and remarks are submitted in the above-identified after Notice of Allowance and concurrently with payment of the issue fee in the application.

Amendments to the Claims

Remarks are included following the amendments.